

INFORMATION DISCLOSURE  
CITATION IN AN  
APPLICATION  
(PTO-1449)



ATTY. DOCKET NO.  
005917 USA/FET/FET

SERIAL NO.  
09/998,372

APPLICANT  
Young Joseph PAIK

FILING DATE  
November 30, 2001

GROUP  
3723

## U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
BB	4,207,520	06/10/80	Flora et al.			04/06/78
	4,209,744	06/24/80	Gerasimov et al.			03/27/78
	4,609,870	09/02/86	Lale et al.			09/13/84
	4,755,753	07/05/88	Chern			07/23/86
	5,427,878	06/27/95	Corliss			05/16/94
	5,534,289	07/09/96	Bilder et al.			01/03/95
	5,867,389	02/02/99	Hamada et al.			11/26/96
	6,041,263	03/21/00	Boston et al.			10/01/97
	6,077,412	06/20/00	Ting et al.			10/30/98
	6,271,670	08/07/01	Caffey			02/08/99
	6,400,162	06/04/02	Mallory et al.			07/21/00
	US 2002/0077031	06/20/02	Johansson et al.			07/06/01
	6,442,496	08/27/02	Pasady et al.			08/08/00
	6,563,308	05/13/03	Nagano et al.			03/27/01
BB	6,587,744	07/01/03	Stoddard et al.			06/20/00

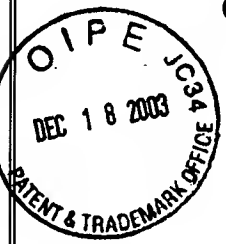
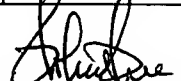
## FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
BB	WO 01/11679	02/15/01	WIPO			X	
BB	WO 01/080306	10/25/01	WIPO			X	

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

BB	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 - 805.
BB	1999. "Contactless Bulk Resistivity/Sheet Resistance Measurement and Mapping Systems." <a href="http://www.Lehighton.com/fabtech1/index.html">www.Lehighton.com/fabtech1/index.html</a> .
BB	2000. "Microsense II Capacitance Gaging System." <a href="http://www.adetech.com">www.adetech.com</a> .
EXAMINER	DATE CONSIDERED 3/29/04


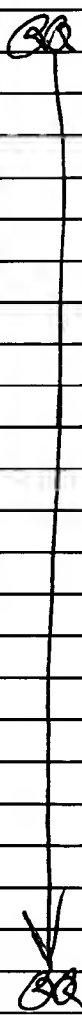
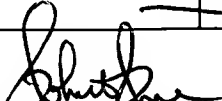
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)</b>  <b>RECEIVED</b> DEC 23 2003 TECHNOLOGY CENTER R3700				ATTY. DOCKET NO. 005917 USA/FET/FET		SERIAL NO. 09/998,372							
				APPLICANT Young Joseph PAIK				FILING DATE November 30, 2001		GROUP 3723			
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<b>OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>													
CB		El Chemali, Chadi et al. July/August 2000. "Multizone uniformity control of a chemical mechanical polishing process utilizing a pre- and postmeasurement strategy." <i>J. Vac. Sci. Technol.</i> Volume 18, No. 4. pp. 1287 – 1296.											
		March 5, 2001. "KLA-Tencor Introduces First Production-worthy Copper CMP In-situ Film Thickness and End-point Control System." <a href="http://www.kla-tencor.com/j/servlet/NewsItem?newsItemID=74">http://www.kla-tencor.com/j/servlet/NewsItem?newsItemID=74</a> .											
		2002. "Microsense II – 5810: Non-Contact Capacitance Gaging Module." <a href="http://www.adetech.com">www.adetech.com</a> .											
		08 August 2003. PCT International Search Report from PCT/US03/08513.											
		14 October 2003. PCT International Search Report from PCT/US02/21942.											
		20 October 2003. PCT International Search Report from PCT/US02/19116.											
		23 October 2003. PCT International Preliminary Examination Report from PCT/US01/24910.											
		"NanoMapper wafer nanotopography measurement by ADE Phase Shift." <a href="http://www.phase-shift.com/nanomap.shtml">http://www.phase-shift.com/nanomap.shtml</a> .											
		"Wafer flatness measurement of advanced wafers." <a href="http://www.phase-shift.com/wafer-flatness.shtml">http://www.phase-shift.com/wafer-flatness.shtml</a> .											
		"ADE Technologies, Inc. – 6360." <a href="http://www.adetech.com/6360.shtml">http://www.adetech.com/6360.shtml</a> .											
V		"3D optical profilometer MicroXAM by ADE Phase Shift." <a href="http://www.phase-shift.com/microxam.shtml">http://www.phase-shift.com/microxam.shtml</a> .											
CB		"NanoMapper FA factory automation wafer nanotopography measurement." <a href="http://www.phase-shift.com/nanomapperfa.shtml">http://www.phase-shift.com/nanomapperfa.shtml</a> .											
EXAMINER						DATE CONSIDERED							
						3/29/04							

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SHEET 1 OF 2

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>   (PTO-1449)				ATTY. DOCKET NO. 005917 USA/FET/FET		SERIAL NO. 09/998,372	
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<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
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	6,245,581 B1	06/12/01	Bonser et al.			04/19/00	
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	6,346,426 B1	02/12/02	Toprac et al.			11/17/00	
	6,363,294 B1	03/26/02	Coronel et al.			12/29/98	
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	6,590,179 B2	07/08/03	Tanaka et al.			02/26/01	
	6,604,012 B1	08/05/03	Cho et al.			08/23/00	
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TECHNOLOGY CENTER R3700

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						Yes	No
BB	0 397 924 A1	11/22/90	Europe			X	

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

BB	Rocha, Joao and Carlos Ramos. September 12, 1994. "Task Planning for Flexible and Agile Manufacturing Systems." <i>Intelligent Robots and Systems '94. Advanced Robotic Systems and the Real World, IROS '94. Proceedings of the IEEE/RSJ/GI International Conference on Munich, Germany 12-16 Sept. 1994.</i> New York, New York: IEEE. pp. 105-112.
	March 15, 2002. Office Action for U.S. Serial No. 09/469,227, filed December 22, 1999.
	March 29, 2002. Office Action for U.S. Serial No. 09/363,966, filed July 29, 1999.
	June 20, 2002. Office Action for U.S. Serial No. 09/619,044, filed July 19, 2000.
	September 26, 2002. Office Action for U.S. Serial No. 09/637,620, filed August 11, 2000.
	October 23, 2002. Office Action for U.S. Serial No. 09/469,227, filed December 22, 1999.
	December 17, 2002. Office Action for U.S. Serial No. 09/363,966, filed July 29, 1999.
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	January 20, 2004. Office Action for U.S. Serial No. 09/927,444, filed August 13, 2001.
	January 23, 2004. International Search Report for PCT/US02/24860.
BB	February 2, 2004. Office Action for U.S. Serial No. 09/363,966, filed July 29, 1999.

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